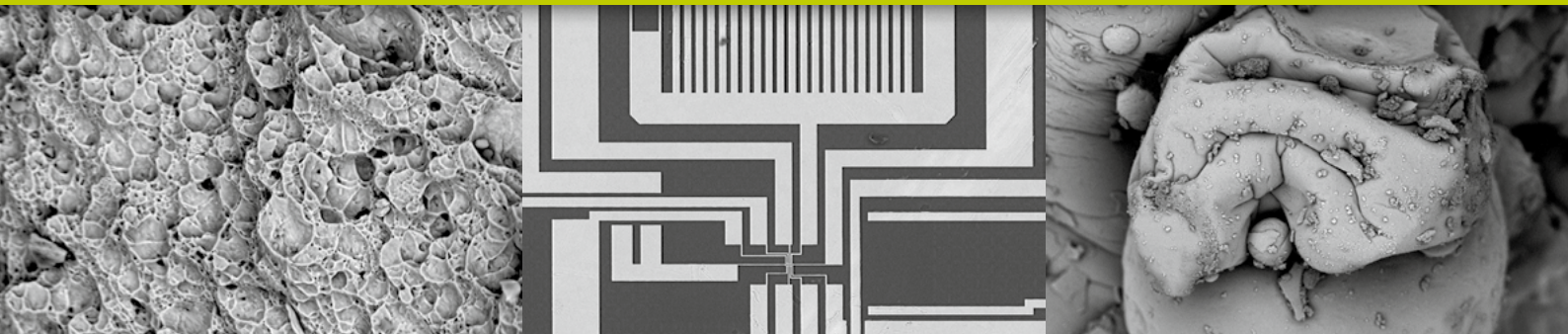




# PHENOM ProX

THE PERFECT ALL-IN-ONE DESKTOP SEM



## ⊕ PHENOM PROX

All-in-one imaging & analysis system

## ⊕ MAGNIFICATION

Magnification range up to 100,000x

## ⊕ NEVER LOST NAVIGATION

Swift navigation to any region of interest

## ⊕ FULLY INTEGRATED EDS

Analysis is as easy as imaging with fully integrated EDS detector and software

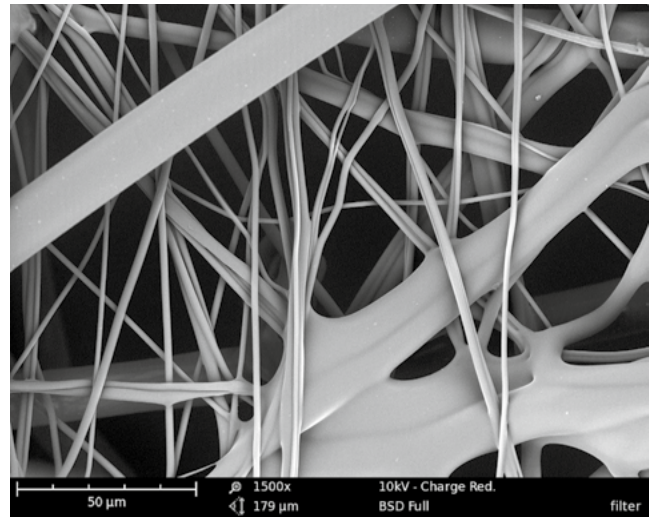
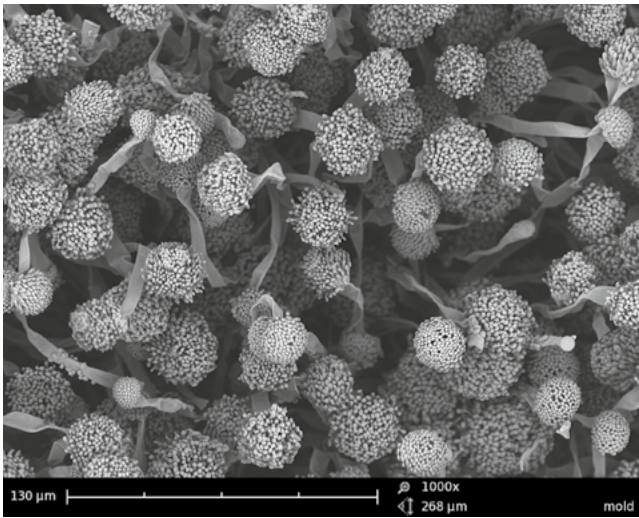
## ⊕ MULTIPLE ACCELERATION VOLTAGES

5 kV and 10 kV for high resolution images;  
15 kV for great analysis results

## ⊕ ELEMENTAL MAPPING & LINE SCAN

Revealing the distribution of elements within the sample

Phenom-World products are of high quality, fast, compact and easy to use. The Phenom ProX™ is the most extended solution for fast and user friendly imaging and analysis.



The Phenom ProX desktop scanning electron microscope (SEM) is the ultimate all-in-one imaging and X-ray analysis system. With the Phenom ProX desktop SEM, sample structures can be physically examined and their elemental composition determined. Besides point analysis, the optional Elemental Mapping and Line Scan software allows further analysis of the distribution of elements.

**PHENOM PROX**

All Phenom-World products are intuitive to use, fast to create results and built to high quality standards. These core principles have been used to develop and create the Phenom ProX spectroscopy system for best-in-class imaging and analysis. As well as viewing three-dimensional images of microscopic structures, there is often a need to identify the different chemical elements in a specimen. This is accomplished in the Phenom

ProX with the Element Identification (EID) software package and a specially designed and fully integrated Energy Dispersive Spectrometer (EDS).

The Phenom ProX is the most extended solution for fast and user friendly imaging and analysis. This is enhanced by additional sample holders that allow for example sample tilting and cooling for imaging an even greater diversity of samples.

**IMAGING SPECIFICATIONS**

**IMAGING MODES**

- Light optical Magnification range: 20 - 120x
- Electron optical Magnification range: 80 - 100,000x
- Digital zoom max. 12x

**ILLUMINATION**

- Light optical Bright field / dark field modes
- Electron optical Long-lifetime thermionic source (CeB<sub>6</sub>)
- Low, imaging, spot analysis and mapping mode, beam currents selection

Acceleration Voltages 5 kV, 10 kV and 15 kV imaging and analysis mode

Resolution ≤ 17 nm

**DIGITAL IMAGE DETECTION**

- Light optical Color navigation camera
- Electron optical High-sensitivity backscattered electron detector (compositional and topographical modes)

**IMAGE FORMATS**

JPEG, TIFF, BMP

**IMAGE RESOLUTION OPTIONS**

456 x 456, 684 x 684, 1024 x 1024 and 2048 x 2048 pixels

**DATA STORAGE**

USB flash drive  
Network  
Pro Suite PC

**SAMPLE STAGE**

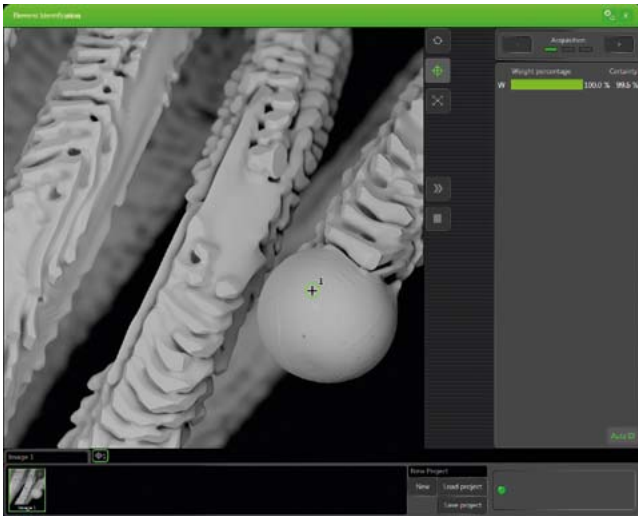
Computer-controlled motorized X and Y

**SAMPLE SIZE**

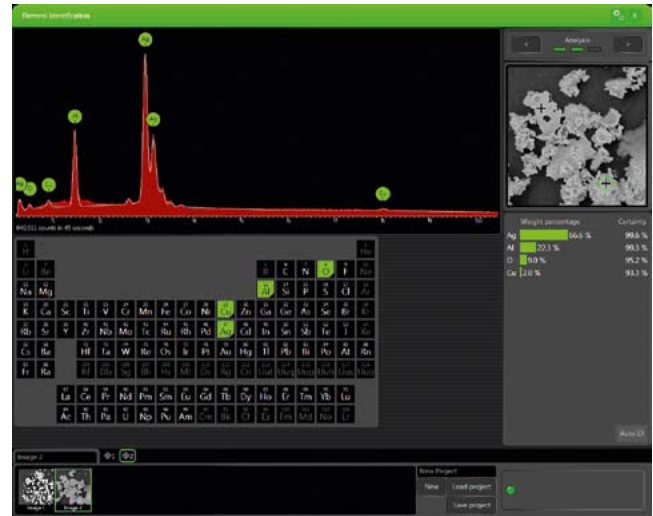
32 mm (Ø); 100 mm (h)

**SAMPLE LOADING TIME**

- Light Optical < 5 s
- Electron Optical < 30 s



Acquisition mode



Spot mode analysis

## STEP-BY-STEP DATA COLLECTION

A dedicated software package is included and installed on the Pro Suite PC to control the fully integrated EDS detector. Analysis has become as easy as imaging, since there is no need to switch between external software packages or computers. The EDS-technique analyzes X-rays generated by the electrons from the electron beam interacting with the sample. The Phenom CeB<sub>6</sub> electron source generates the highest number of X-rays in its market segment.

The element identification software package allows the user to identify any hidden elements within the sample via the spot mode analysis. All results are verified using iterative peak stripping deconvolution. The step-by-step guided process within the software helps the user to collect all X-ray results in an organized and structured way. Optionally, this software can be expanded with the Elemental Mapping and Line Scan option.

## EDS SPECIFICATIONS

|                         |   |
|-------------------------|---|
| <b>DETECTOR TYPE</b>    | Silicon Drift Detector (SDD)<br>Thermoelectrically cooled (LN <sub>2</sub> free)  |
| Detector active Area    | 25 mm <sup>2</sup>  |
| X-ray window            | Ultra-thin Silicon Nitride (Si <sub>3</sub> N <sub>4</sub> ) window allowing detection of elements C to Am  |
| Energy resolution       | Mn Kα ≤ 140 eV  |
| Processing capabilities | Multi-channel analyzer with 2048 channels at 10 eV/ch   |
| Max. input count rate   | 300,000 cps   |
| Hardware integration    | Fully embedded  |
| <b>SOFTWARE</b>         | Integrated in Phenom Pro Suite<br>Integrated column and stage control<br>Auto-peak ID<br>Iterative strip peak deconvolution<br>Confidence of analysis indicator<br>Export functions: CSV, JPG, TIFF, ELID, EMSA |
| <b>REPORT</b>           | Docx format   |

## SYSTEM SPECIFICATIONS

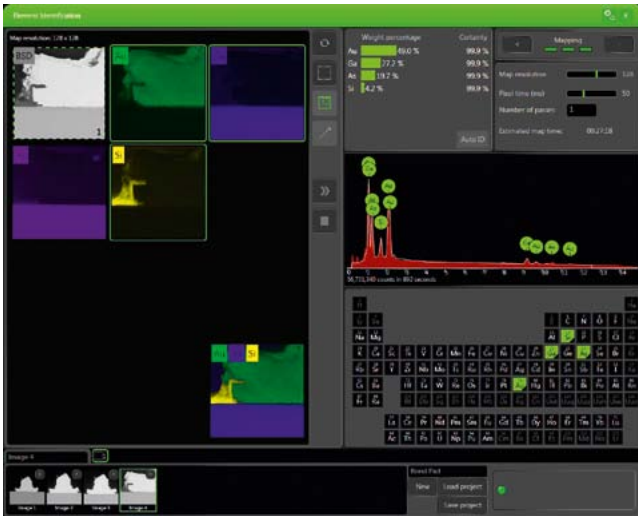
|                                |   |
|--------------------------------|---|
| <b>DIMENSIONS &amp; WEIGHT</b> |   |
| Imaging module                 | 286(w) x 566(d) x 495(h) mm, 50 kg  |
| Diaphragm vacuum pump          | 145(w) x 220(d) x 213(h) mm, 4.5 kg   |
| Power supply                   | 156(w) x 300(d) x 74(h) mm, 3 kg  |
| Monitor                        | 375(w) x 203(d) x 395(h) mm, 7.9 kg   |
| Pro Suite                      | Standard Pro Suite System including:<br>19" monitor with PC and network router mounted<br>375(w) x 250(d) x 395(h) mm, 9 kg |

## REQUIREMENTS

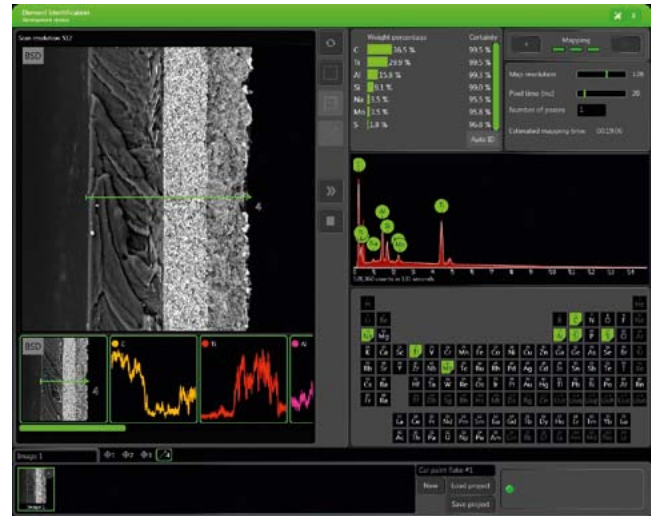
|                           |  |
|---------------------------|--|
| <b>AMBIENT CONDITIONS</b> |  |
| Temperature               | 15°C ~ 30°C (59°F ~ 86°F)                              |
| Humidity                  | < 80% RH   |
| Power                     | Single phase AC 110 - 240 Volt, 50/60 Hz, 300 W (max.) |

## RECOMMENDED

|                   |                                    |
|-------------------|------------------------------------|
| <b>TABLE SIZE</b> | 150 x 75 cm, load rating of 100 kg |
|-------------------|------------------------------------|



Selected Area Mapping



Line Scan analysis

**ELEMENTAL MAPPING AND LINE SCAN**

Elemental Mapping reveals the distribution of elements within the sample. The selected elements can be mapped at a user specified pixel resolution and acquisition time. The real time mapping algorithm shows live build-up of the selected element maps while storing spectra of each pixel. This allows elements to be added or removed at any time during or after the mapping process. Mixing any number of elements with the backscatter image gives users a clear insight into the distribution of elements within the sample.

Mapping can be done on the image as a whole or to save time, on a Selected Area (SA). Any area can be selected in a rectangular shape on the image location. Line Scan allows analysis to be performed over a selected line. The number of points and dwell time per point can be selected individually. A line profile of every selected element is displayed on the screen. On top of that, the results can be easily exported and reported via an automated template. Multiple analyses can be performed in sequence without user intervention.

**ELEMENTAL MAPPING & LINE SCAN SPECIFICATIONS**

**ELEMENTAL MAPPING**

|                          |   |
|--------------------------|---|
| Element selection        | 10 individual user-specified maps, plus backscatter image and mix-image |
|                          | Selected area Any size, rectangular shaped                              |
| Mapping resolution range | 16x16 - 512x512 pixels  |
| Pixel dwell time range   | 10 - 250 ms   |

**LINE SCAN**

|                            |                 |
|----------------------------|-----------------|
| Line Scan resolution range | 16 – 512 pixels |
| Points dwell time range    | 50 – 250 ms     |
| Total number of lines      | 12              |

**REPORT**

Docx format